



University of
Nottingham

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MANUFACTURING
METROLOGY TEAM

On development of a fast wireless focus variation probe for in-process surface measurement

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University of Nottingham

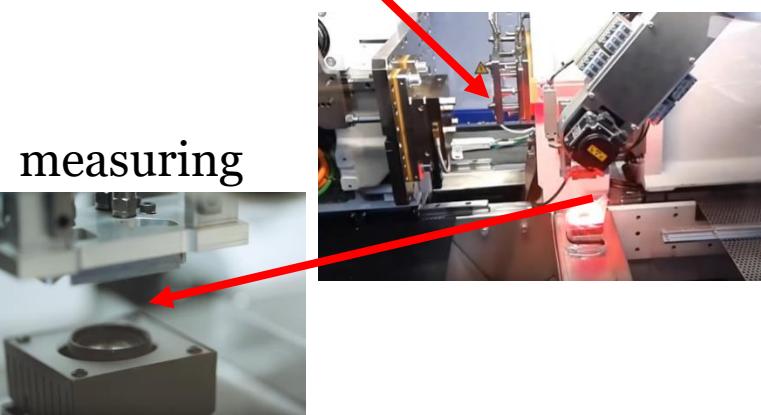
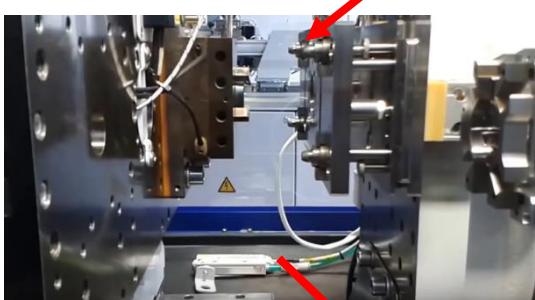


alicona
imaging

Motivation

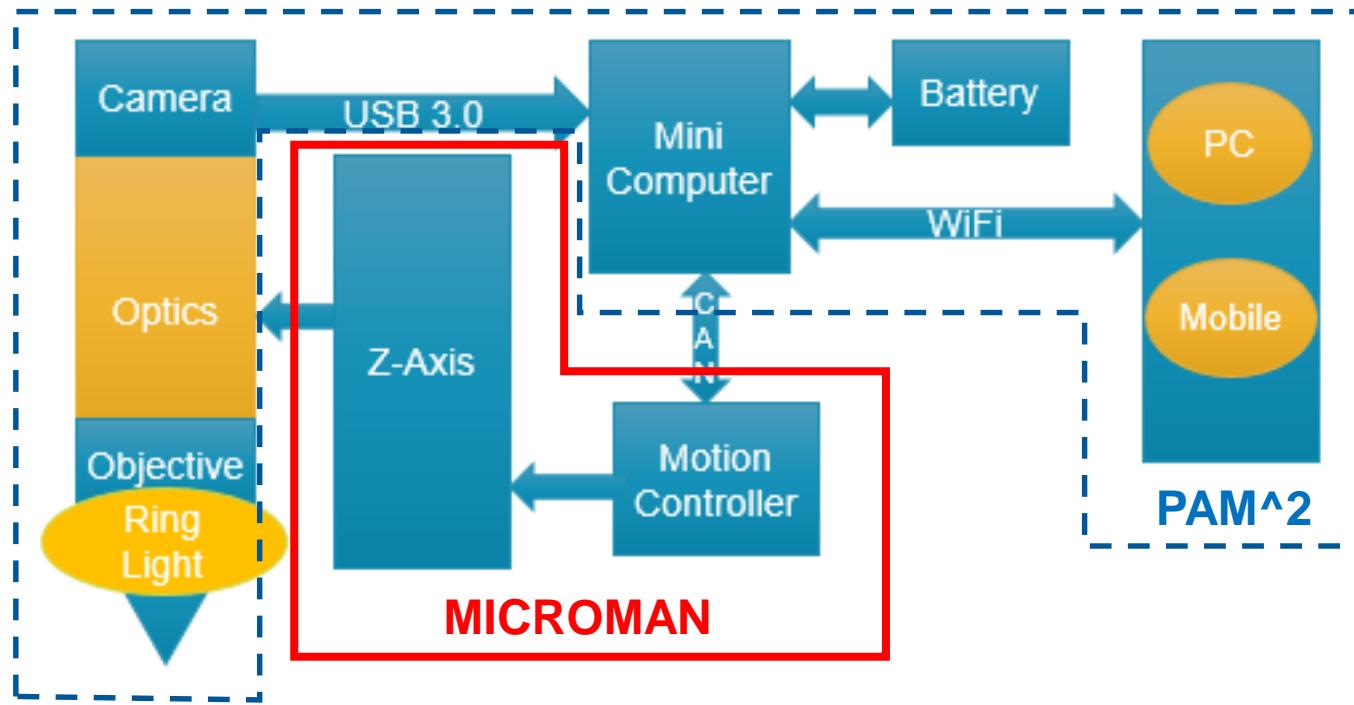
- The need of a small and compact surface measurement sensor to be easily integrated into various production machines

Micro injection moulding and CNC machine



MICROMAN Marie-Curie ITN Project

General project scope:



Company partner:
Alicona GmbH



MICROMAN project

- Title: Process Fingerprint for Zero-defect Net-shape **MICROMANufacturing**
- Period: 2015-2019
- Covering major micro-scale manufacturing processes (injection moulding, EDM, ECM, etc)
- 13 PhDs, 8 Universities, 1 RTC
- 5 EU countries: DK, DE, UK, IT, BE



Teguh Santoso

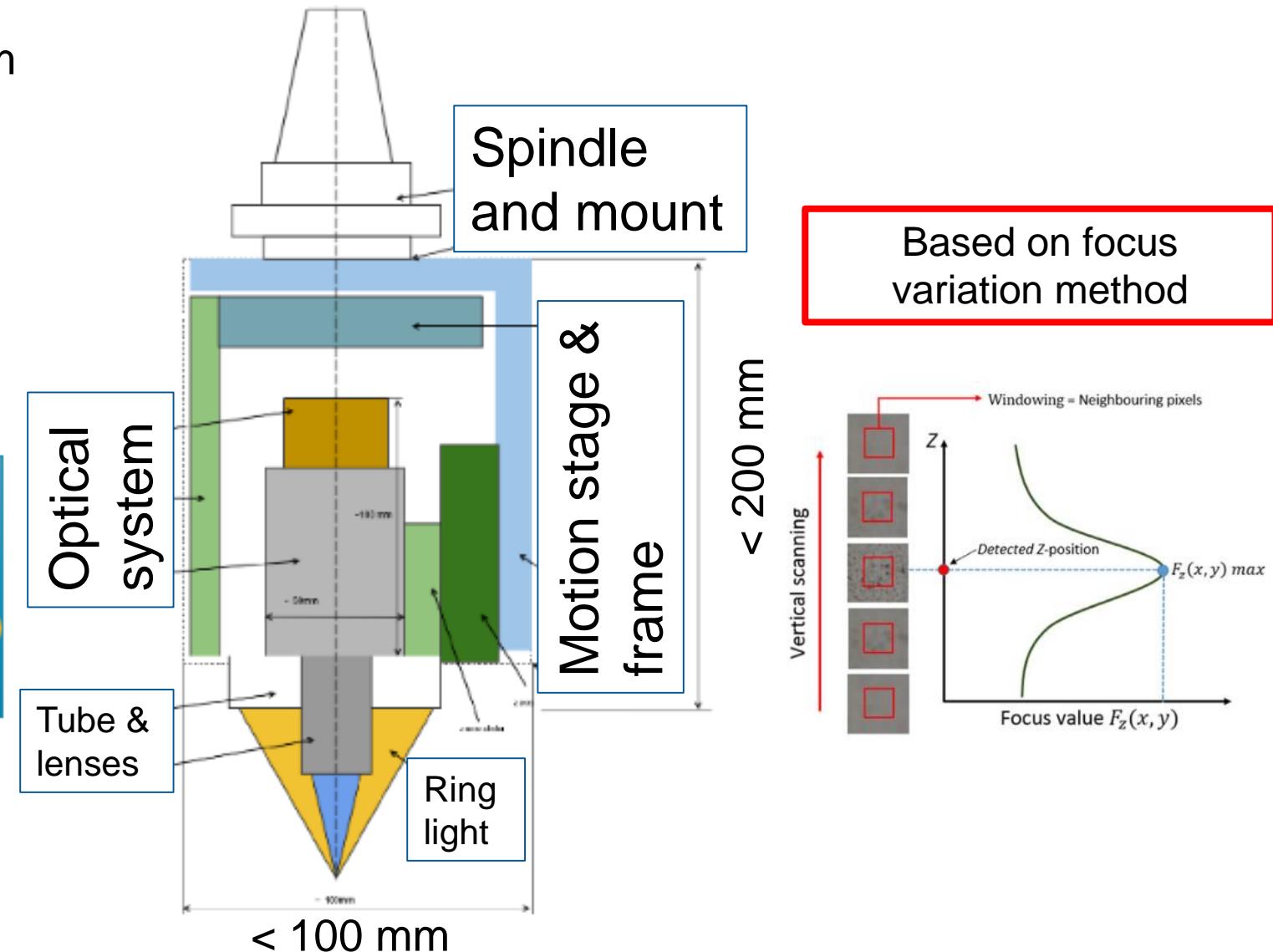
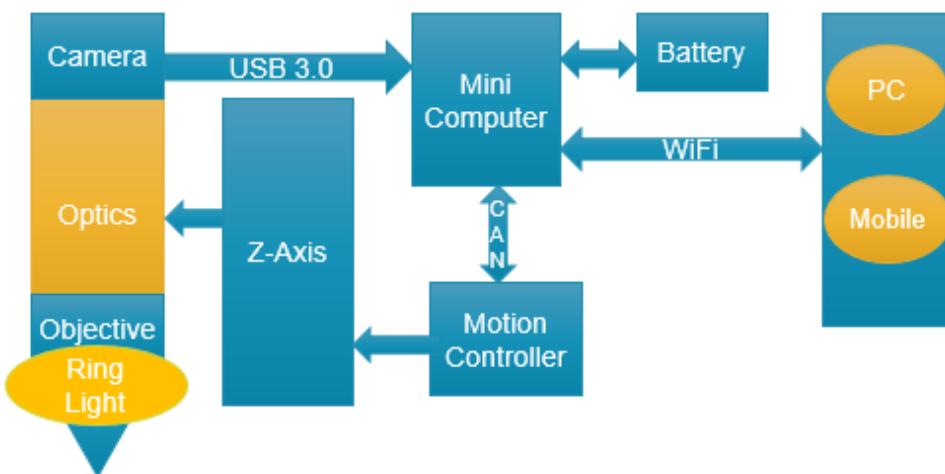


Subbareddy Darukumalli

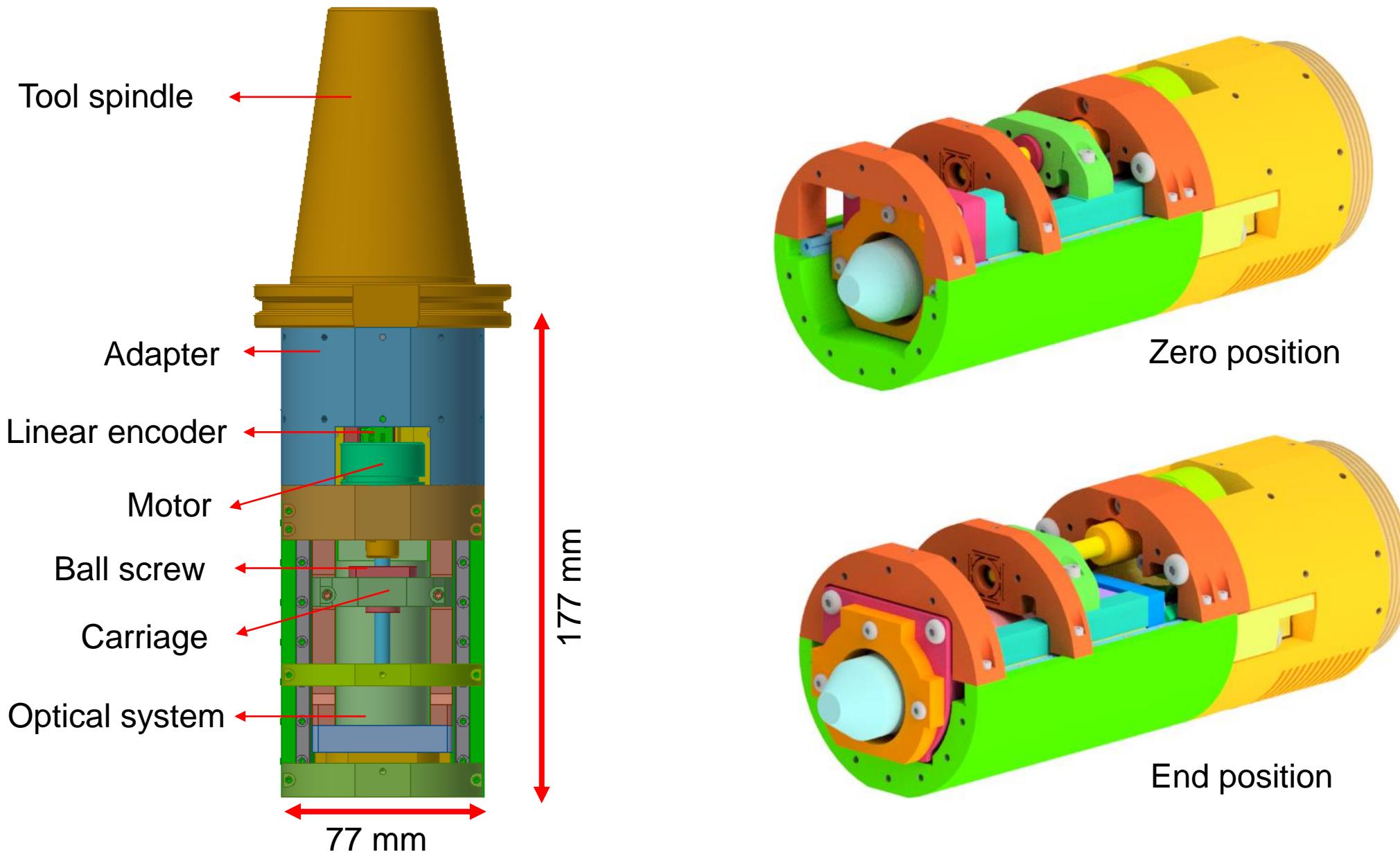


Design requirement

- Absolute position accuracy: $< 1 \mu\text{m}$
- Resolution: $< 25 \text{ nm}$
- Repeatability: $< 250 \text{ nm}$
- Pitch: $< 20 \mu\text{rad}$
- Yaw: $< 20 \mu\text{rad}$
- Straightness: $< 1 \mu\text{m}$



3D CAD model and engineering simulations

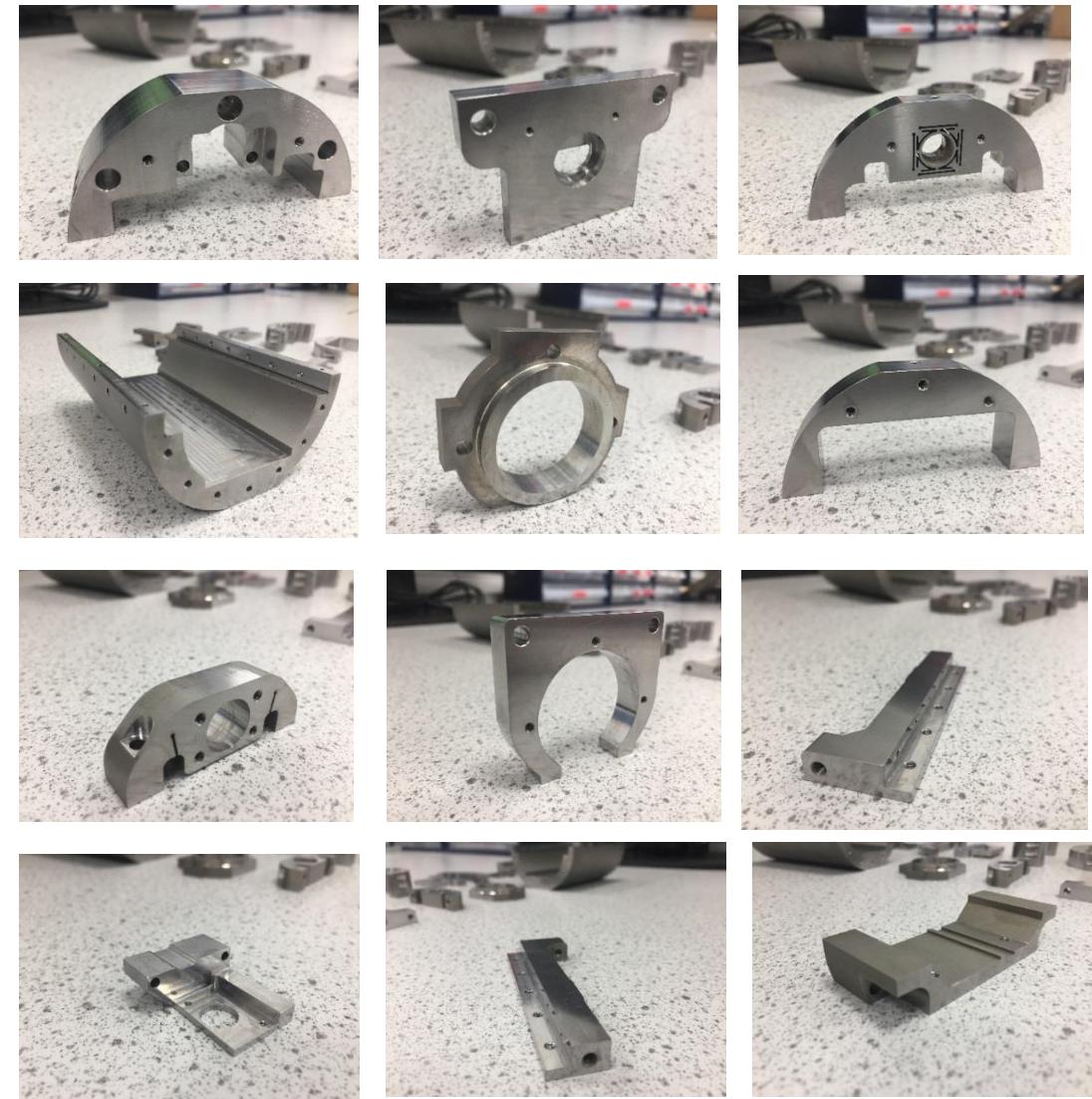
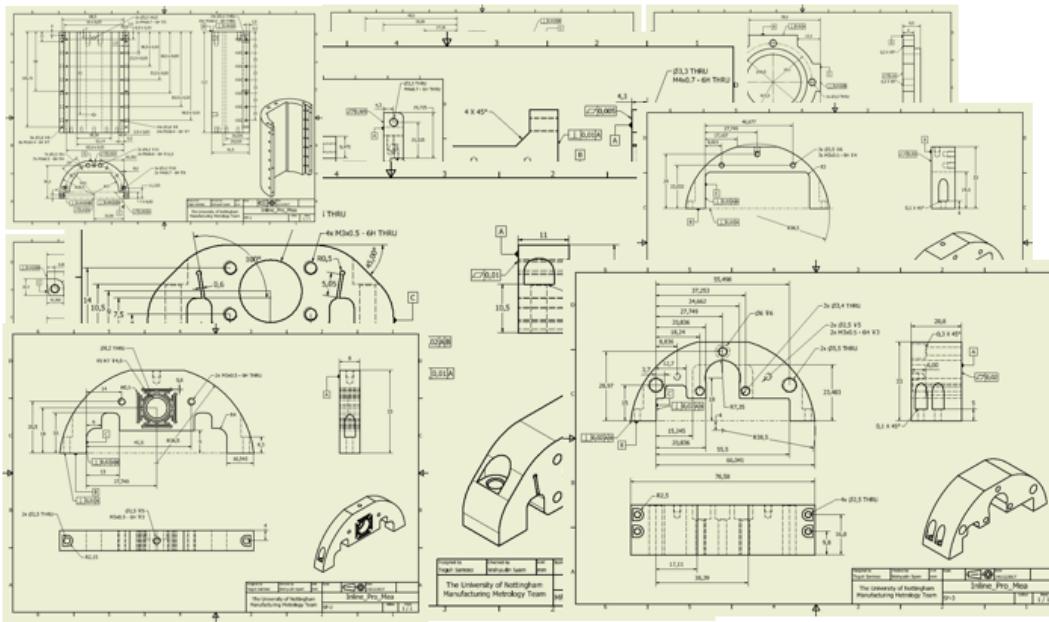


Parts manufacturing

Acknowledgement:

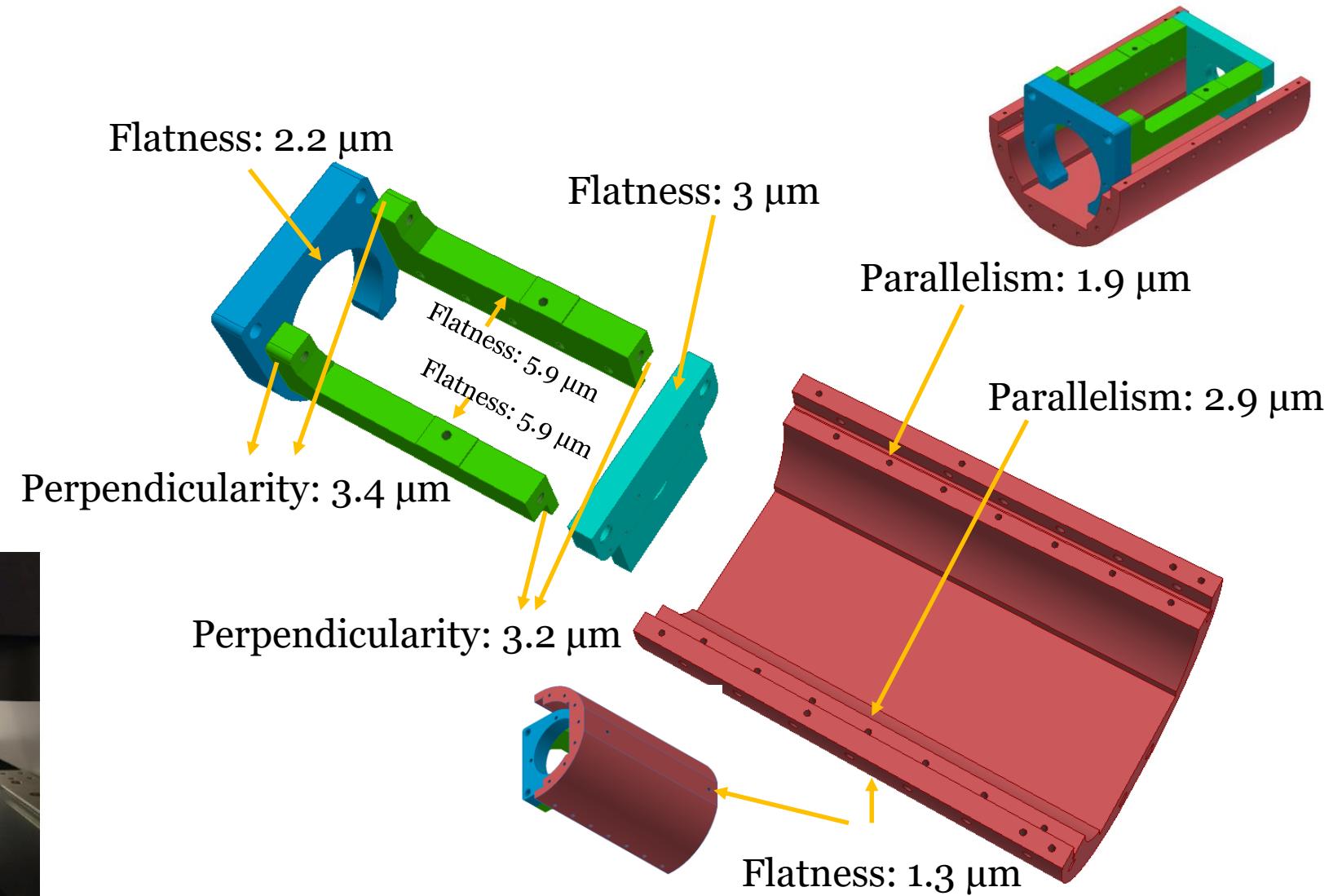
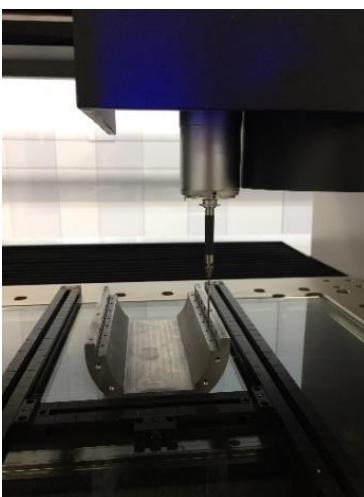
Precision Manufacturing Center (IfAM, University of Nottingham)

- Wire-EDM
- Precision milling
- Grinding
- Material SS416



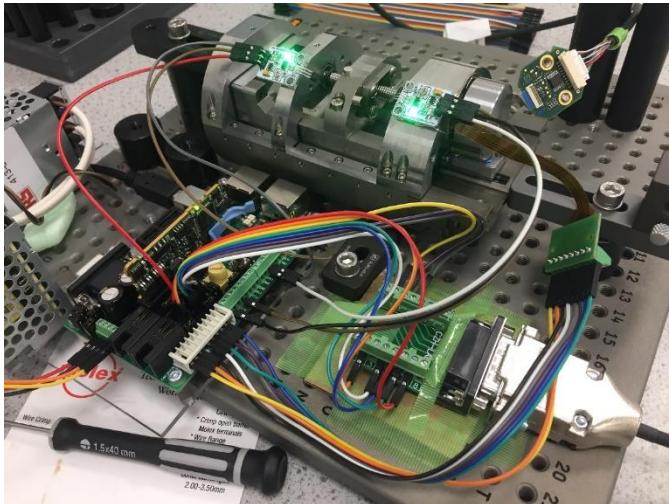
Tolerance verification

- Using tactile CMM

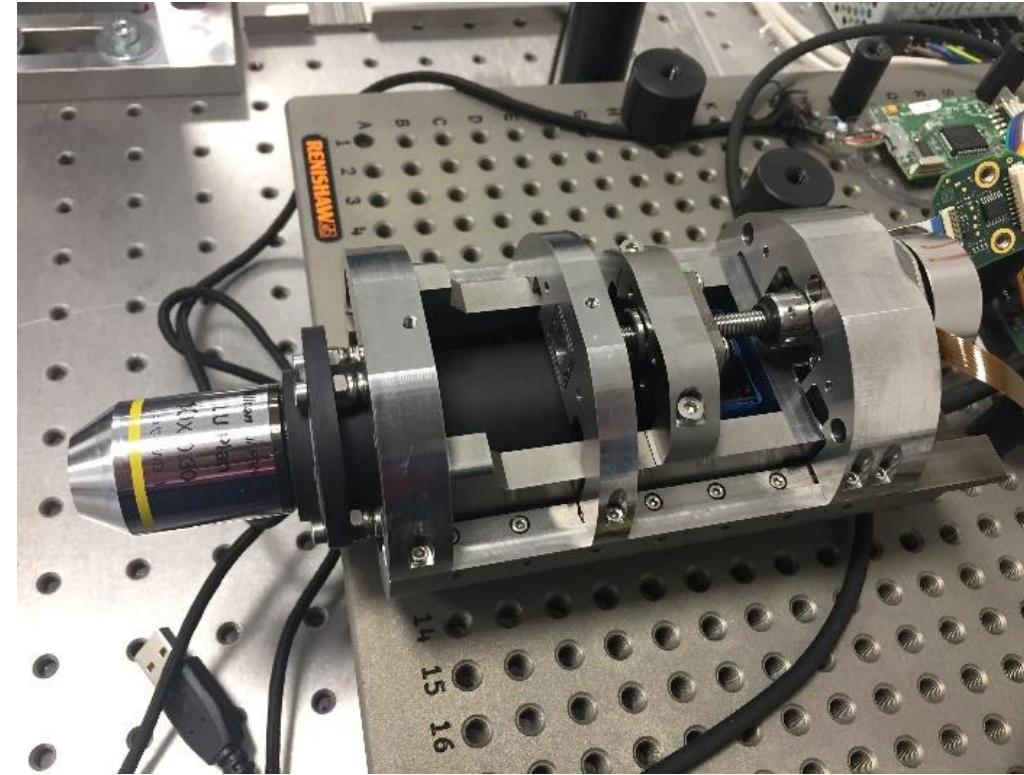


Sensor assembly

Motion controller and driver



Optical system + motion stage



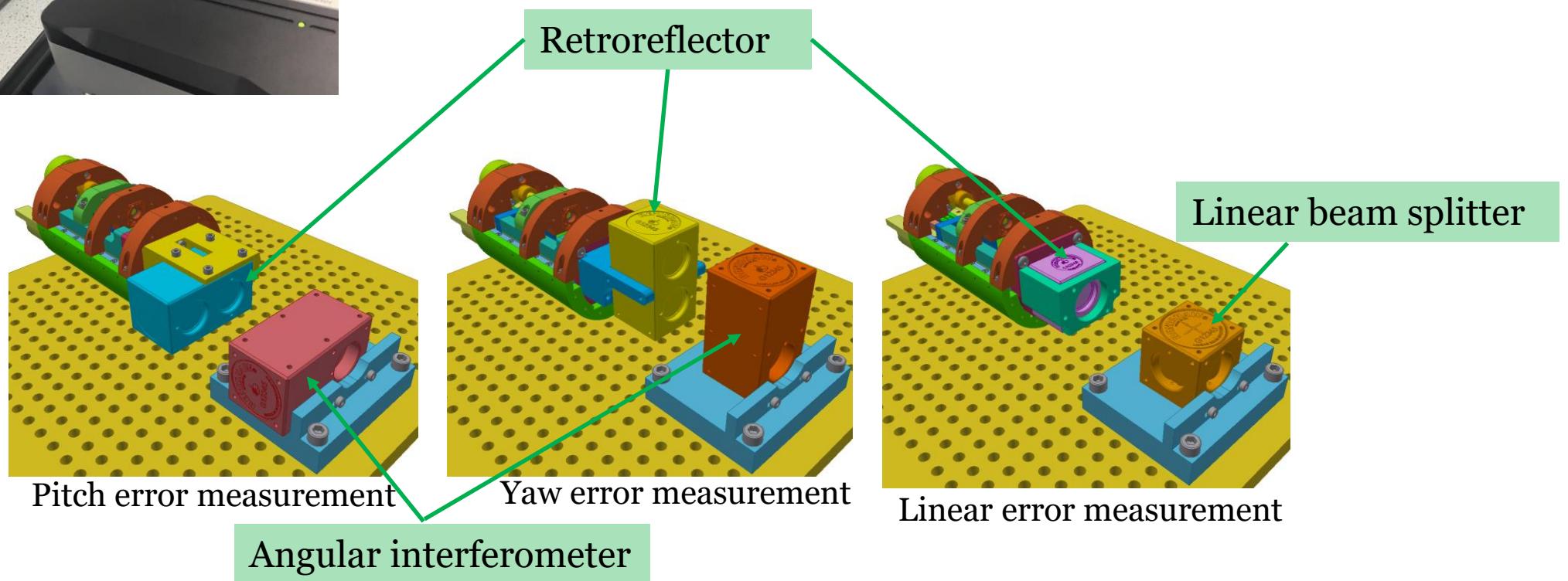
The optical system



10x objective lens

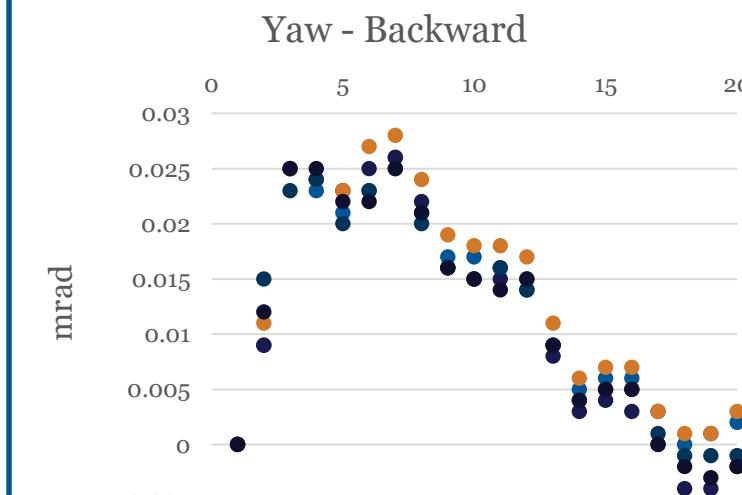
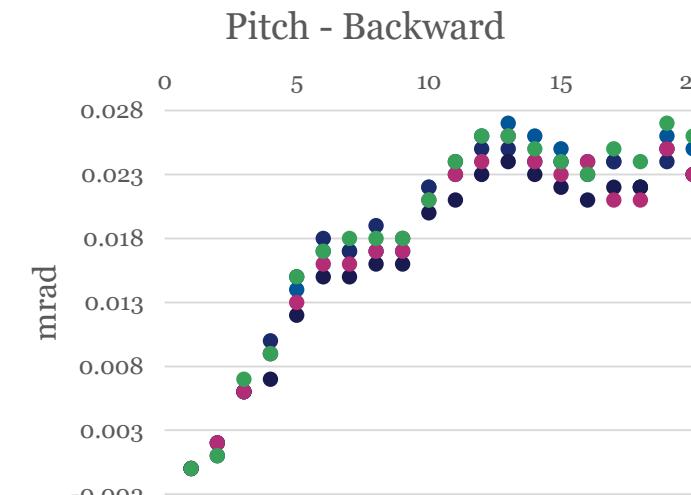
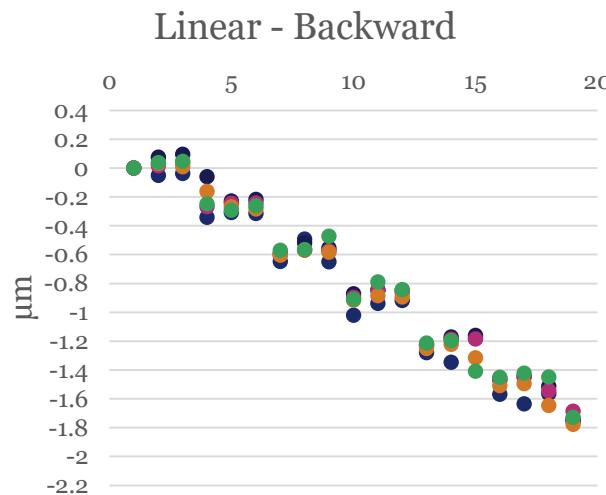
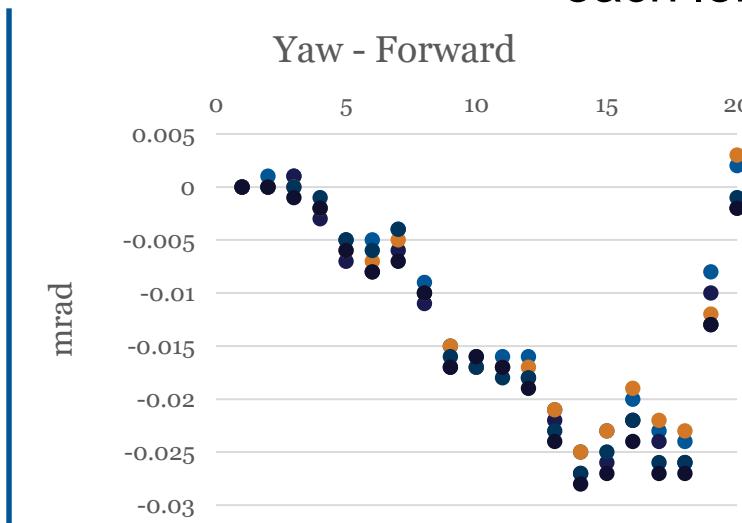
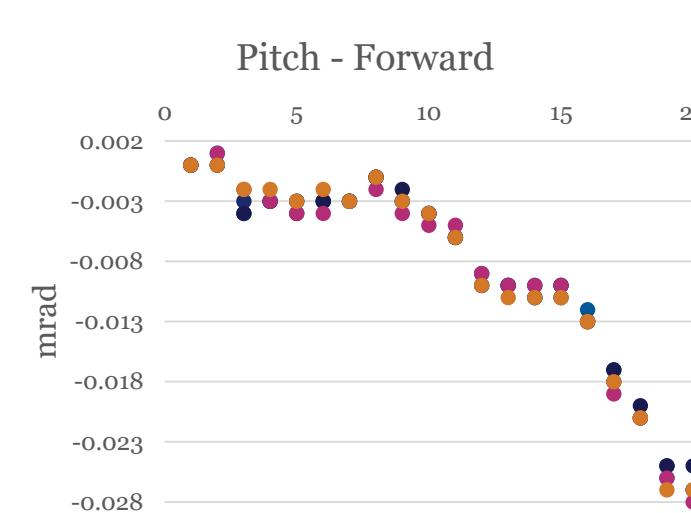
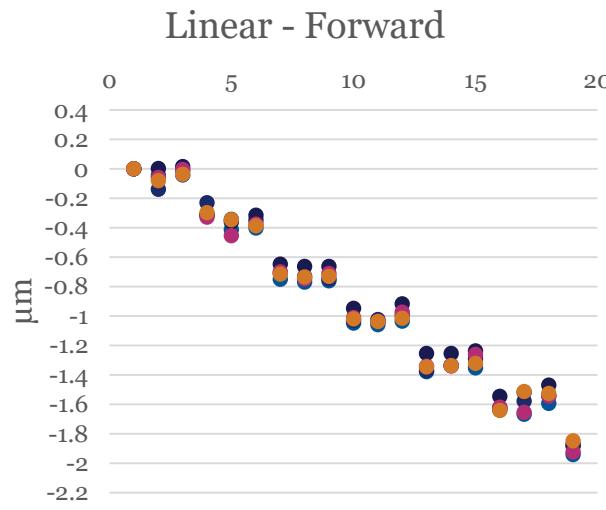
Single axis calibration

- Using a laser interferometer
- The largest standard uncertainty ($k = 1$) = $0.1 \mu\text{m}$ for 20 mm (max. travel length)



Single axis calibration - results

Linear travelling range: 0 – 20 mm



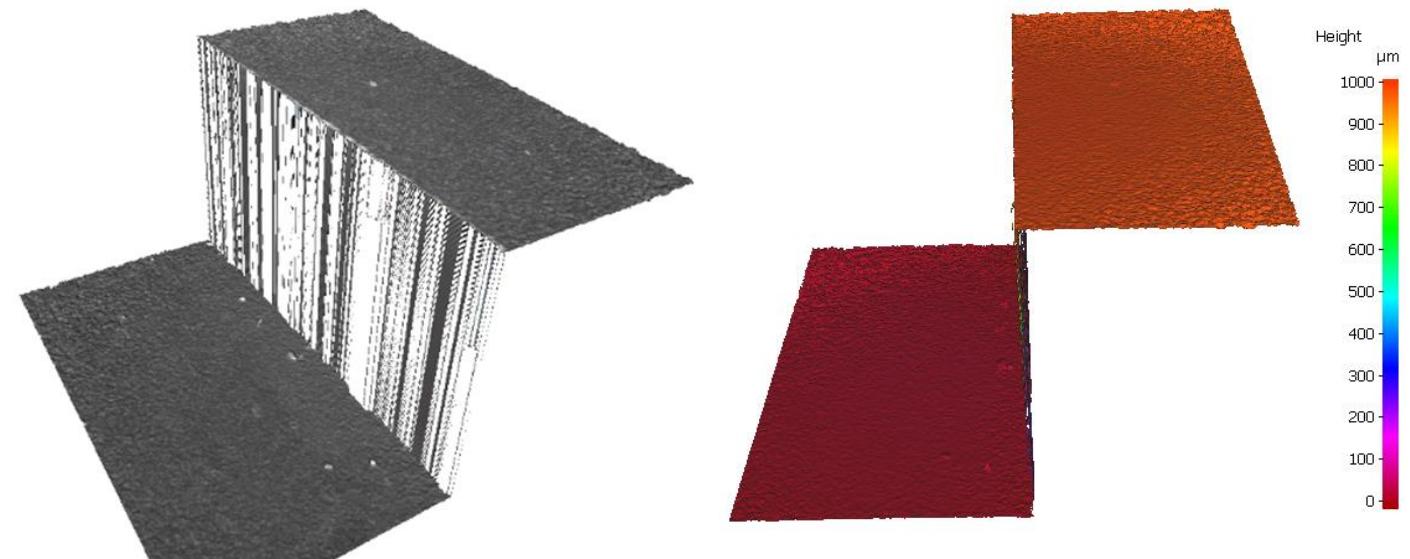
5 repetitions for
each length

Alicona calibrated artefact:



Measurement tests:

- Step height measurement = 1001 µm
Calibration value = 999.99 ± 0.1 µm
- Measurement noise with 10x lens ~ 90 nm





Future works:

- Optical aberration and distortion correction
- Motion control optimisation
- Full system integration: Precision optics + motion stage + mini PC + wifi system
- Metrological characterisation determination based on ISO 25178 series
- Testing on real case studies: micro-scale milling, micro-scale laser milling, etc



Manufacturing Metrology Team at Nottingham

Thank you!



Horizon 2020



EPSRC Centre for Doctoral Training
in Ultra Precision Engineering

EPSRC
Engineering and Physical Sciences
Research Council



EPSRC Centre
for Doctoral Training
in Additive Manufacturing

EMPIR



EURAMET

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